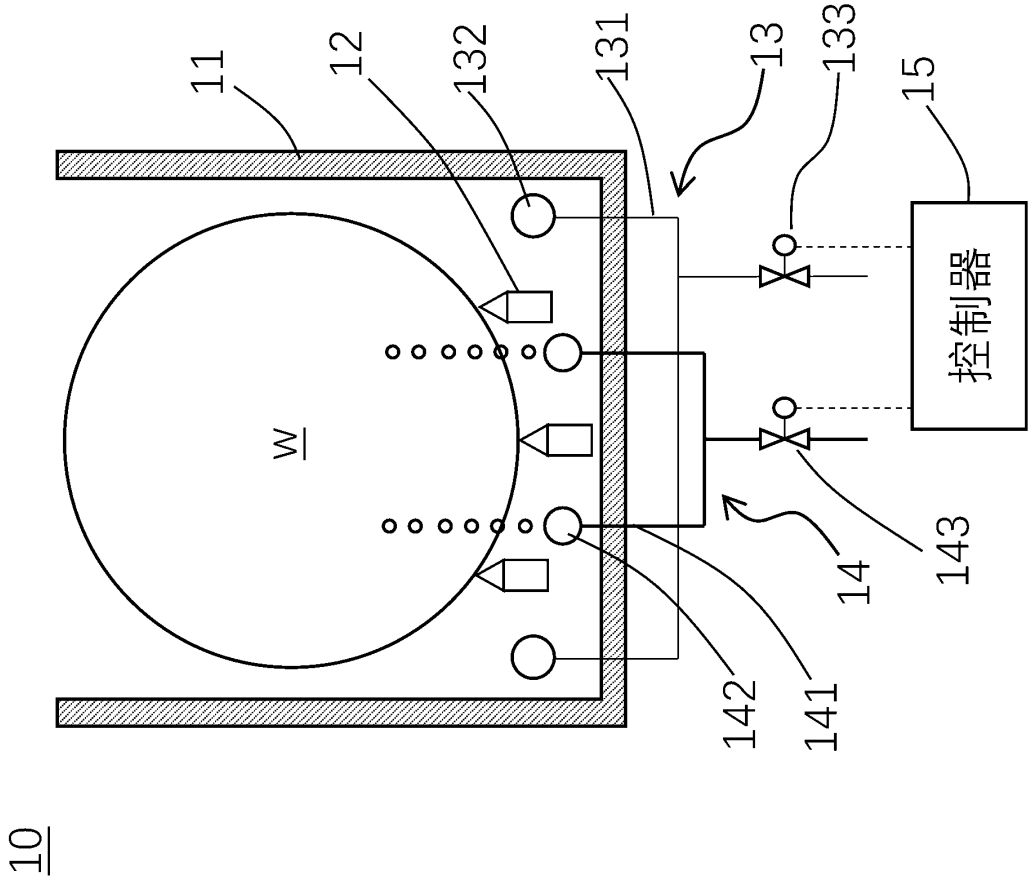


图 1

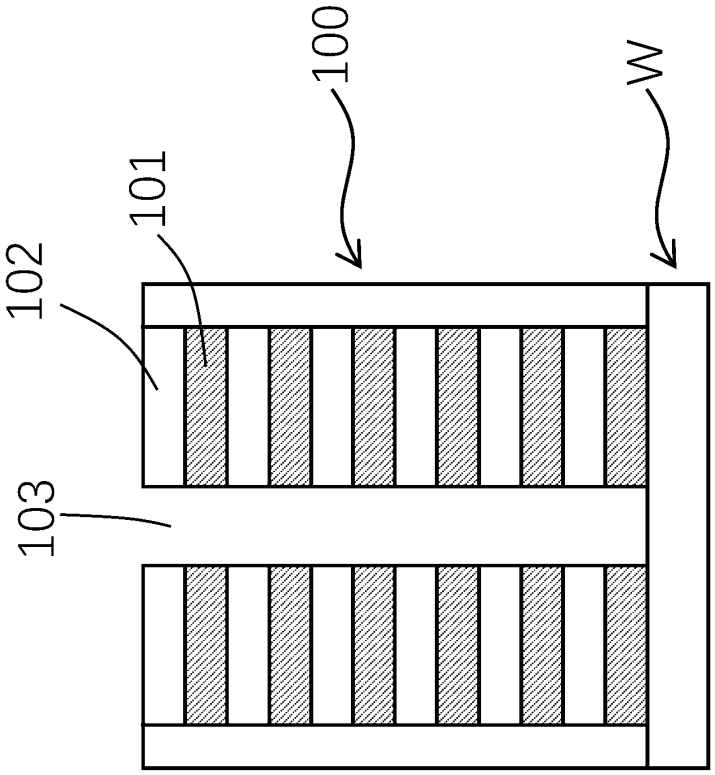


图 2

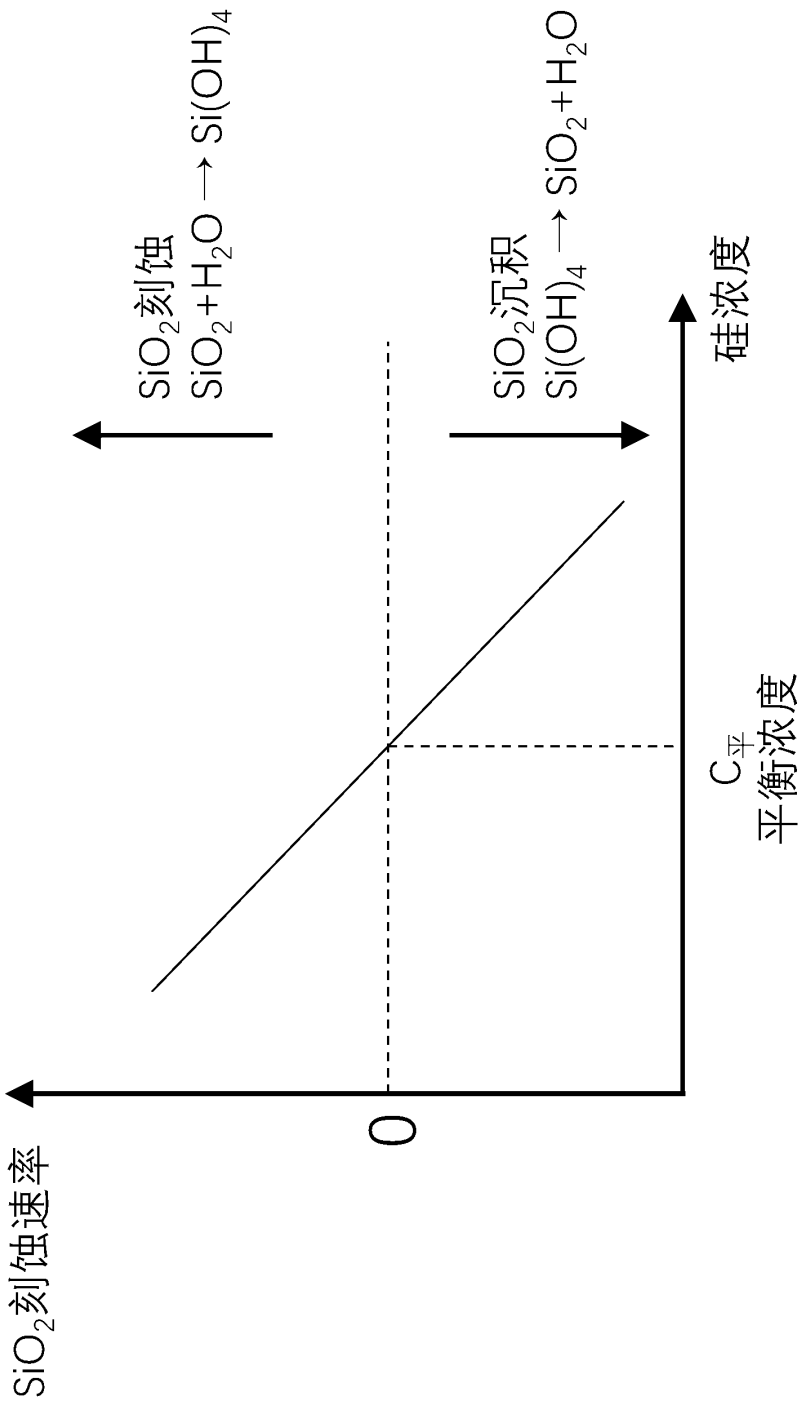

SiO_2刻蚀速率
0
硅浓度
$C_{平}$
平衡浓度
SiO_2刻蚀
$SiO_2+H_2O \longrightarrow Si(OH)_4$
SiO_2沉积
$Si(OH)_4 \longrightarrow SiO_2+H_2O$

图 3

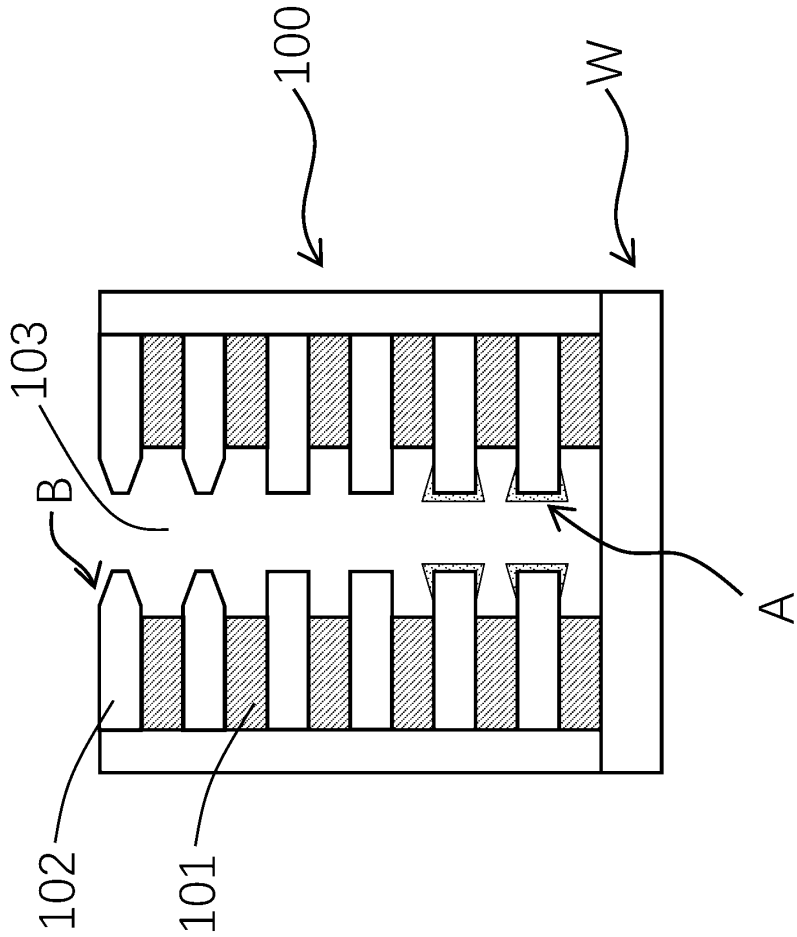


图 4

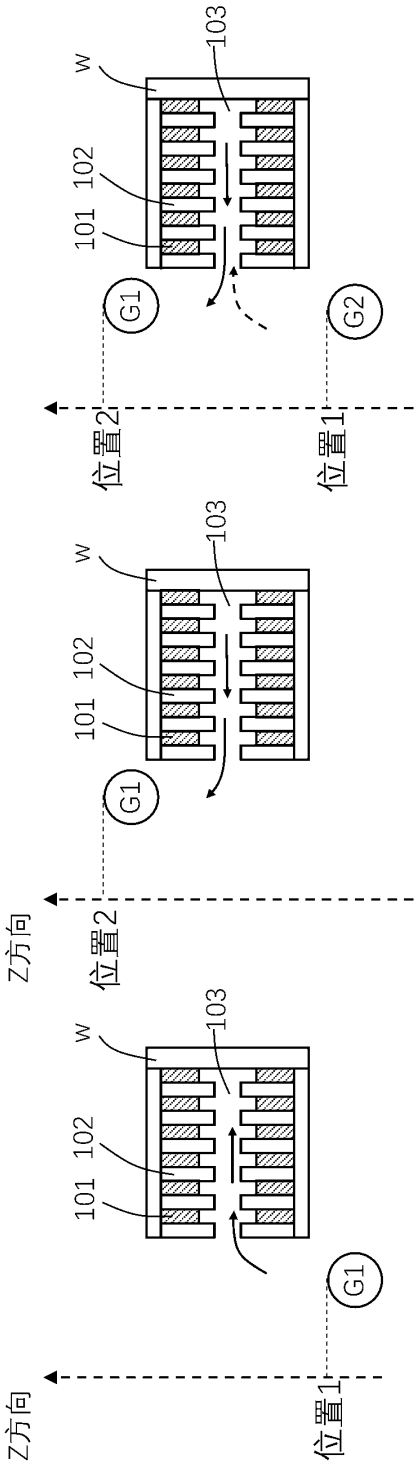


图 5

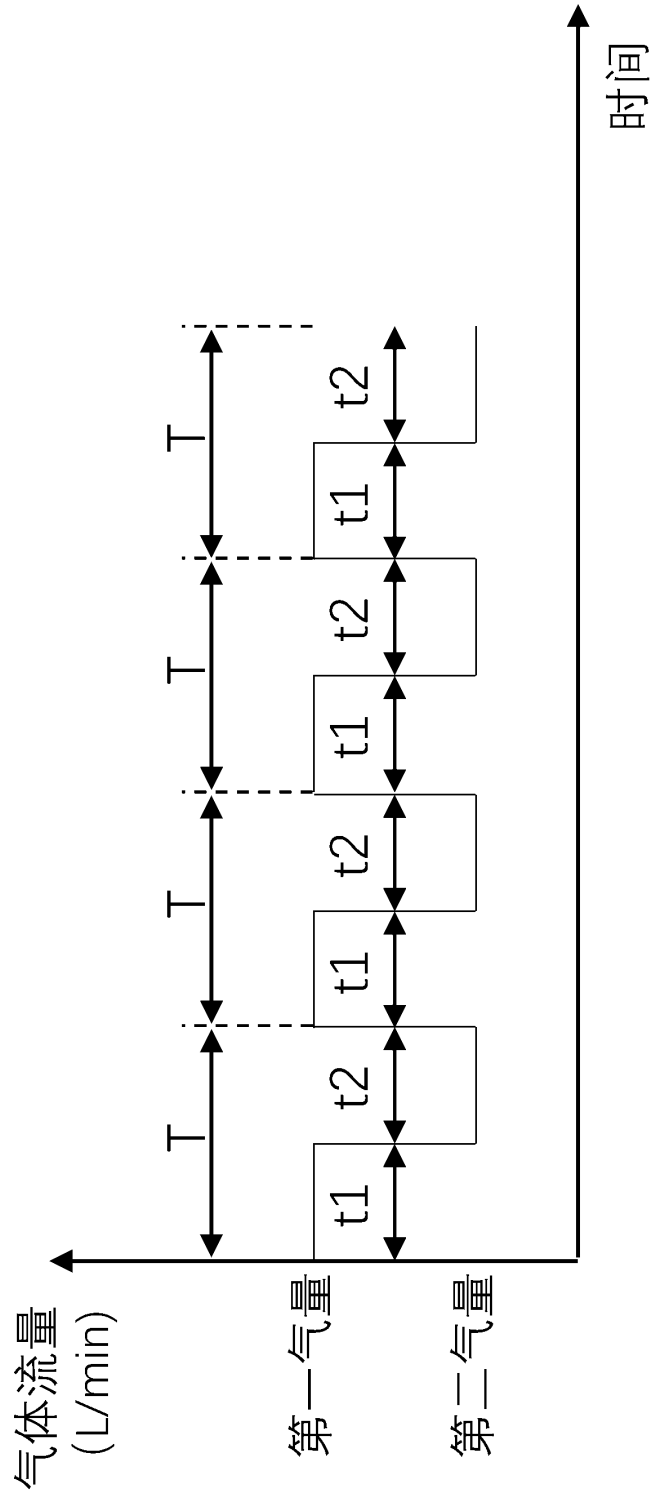


图 6

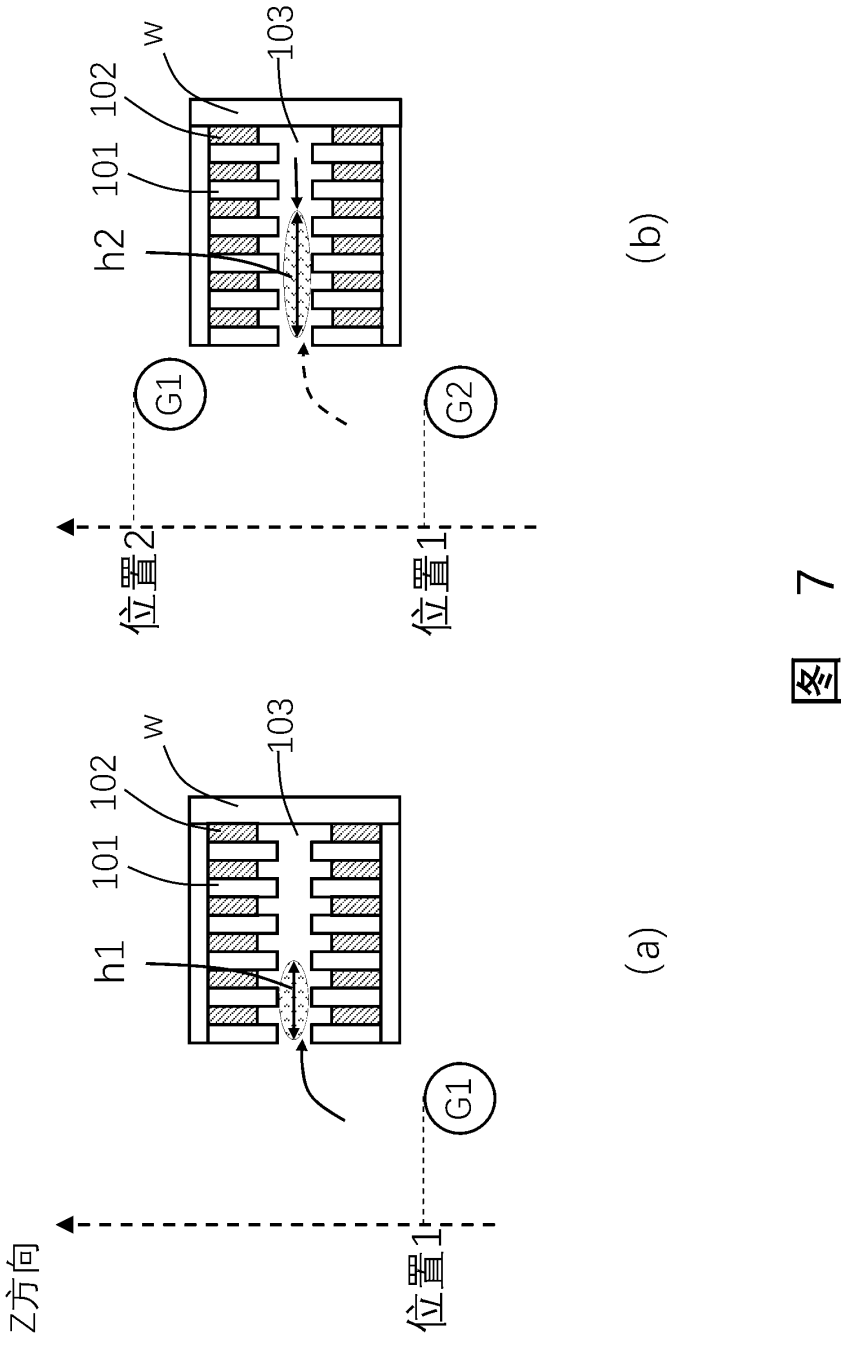


图 7

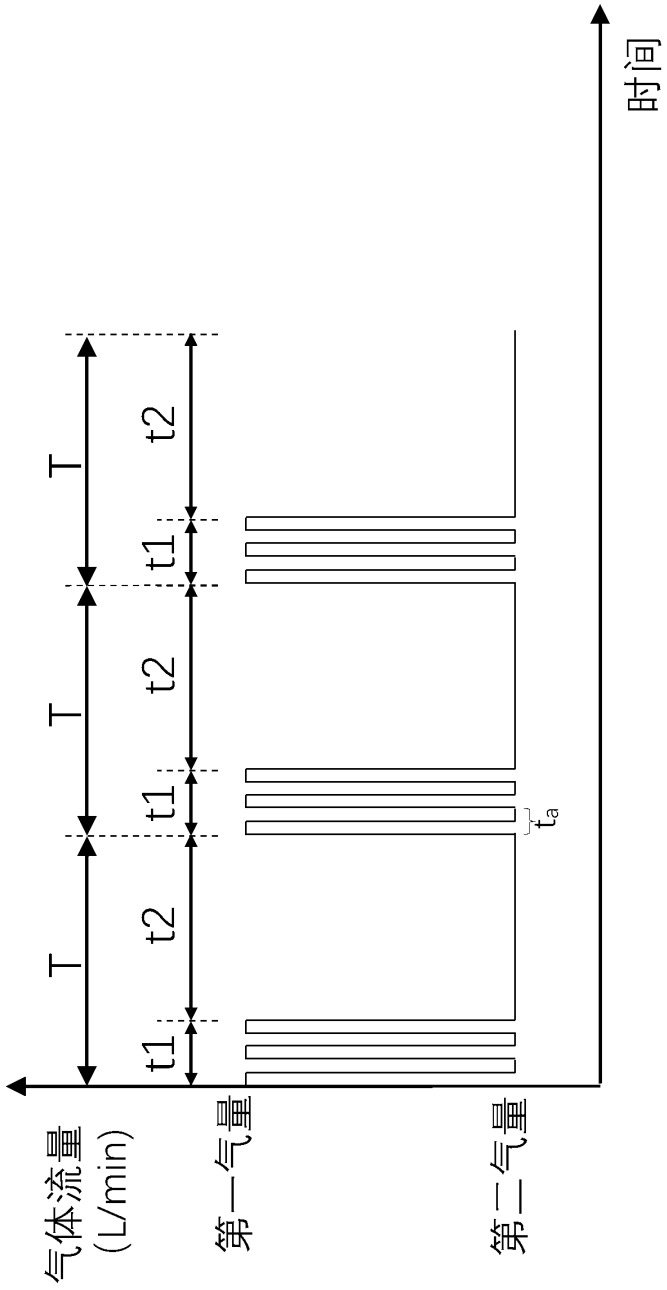


图 8

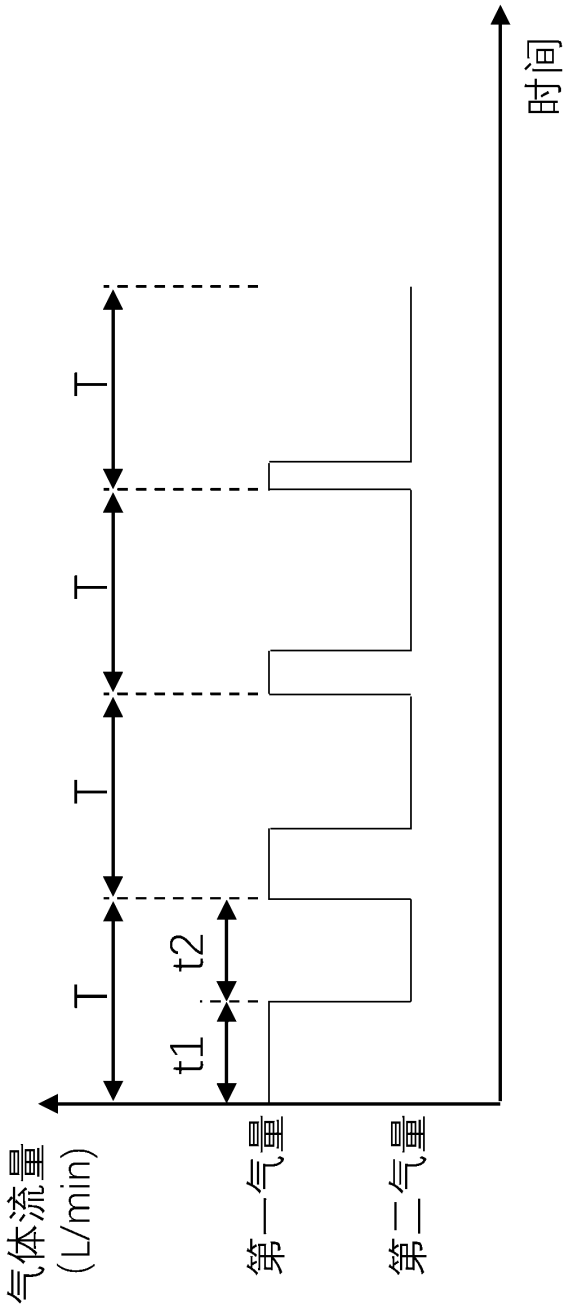


图 9